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	АН	5,239,188	08-24-1993	Takeuchi et al.			
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	AF3	5,733,796	03-31-1998	Manabe et al.		
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	AB5	6,084,899	07-04-2000	Shakuda		
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\$N	AB8	5,252,499	10-12-1993	Rothschild			
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1	AM	JP 52/028887	03-04-1977	Fujitsu LTD		х
	AN	JP 05-243614	09-21-1993	Sharp Corp		х
	AO .	JP 4236478	08-25-1992	Pioneer Electron Corp	_	X
	АР	ЛР 03-218625	09-26-1991	Univ Nagoya		Х
	AQ	JP 03-252177 (abstract only)	11-11-1991	Toyoda Gosei Co LTD Toyoda Central Res & Dev Lab Univ Nagoya Res Dev Corp of Japan		
1	AL2	JP 54-093380	07-24-1979	Fujitsu LTD		Х
	AM2	JP 9092880 (abstract only)	04-04-1997	Toyoda Gosei Co LTD		
	AN2	ЛР 8213692	08-20-1996	Hitachi LTD		Х
	AO2	JP 11145513 (abstract only)	05-28-1999	Sharp Corp		
	AP2	· JP 04-068579	03-04-1992	Sharp Corp		X
	AQ2	JP 02-229475	09-12-1990	Nippon Telegr & Teleph Corp		Х
	AL3	JP 04-242985 (abstract only)	08-31-1992	Toyoda Gosei Co LTD Akasaki Isamu Amano Hiroshi		
十	AM3	JP9134881 (abstract only)	05-20-1997	Matsushita Electron Corp		
	AN3	JP 59-228776	12-22-1984	Nippon Telegr & Teleph Corp		Х
	AO3	JP 06-177423	06-24-1994	Nichia Chem Ind LTD		х
	AP3	ЛР 06-268259	09-22-1994	Nichia Chem Ind LTD		Х
	AQ3	JP 02-229475	09-12-1990	Nippon Telegr & Teleph Corp		х
	AL4	JP 2229475	09-12-1990	Nippon Telegr & Teleph Corp		х
	AM4	JP 06-021511	01-28-1994	Nippon Telegr & Teleph Corp		х
	AN4	JP 4209577	07-30-1992	Nippon Telegr & Teleph Corp		х
	/AO4	JP 61-056474	03-22-1986	Matsushita Electric Ind Co LTD		х
M/	AP4	JP 8167735	06-25-1996	Hitachi Cable LTD		x

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M		AQ4	JP 03-203388	09-05-1991	Matsushita Electric Ind Co LTD		
	1	AL5	JP 8306958	11-22-1996	Sanyo Electric Co LTD		X
		AM5	JP 8306643	11-22-1996	Sumitomo Chem Co LTD		Х
		AN5	JP 8316527	11-29-1996	Sanyo Electric Co LTD		X
		AO5	EP 0 483 688 A2	05-06-1992	Toyoda Gosei Co LTD Nagoya University Research & Development Corporation of Japan		
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#	Z	AO6	EP 0 356 059 A2	02-28-1990	Gertrude F. Neumark		
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	AY	Goldenberg, B., et al., "Ultraviolet and violet light-emitting GaN diodes grown by low-pressure metalorganic chemical vapor deposition," Appl. Phys. Lett. 62(4):381-383 (1993).
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